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Telephone 202.822.4554

Facsimile 202.478.1771

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<b>To:</b>	United States Patent and Trademark Office	<b>From:</b>	Jonathan A. Hack
<b>Fax:</b>	703.872.9306	<b>Pages:</b>	11 (including cover sheet)
<b>Phone:</b>		<b>Date:</b>	December 20, 2004
<b>Re:</b>	U.S. Application No.: 10/085,753	<b>CC:</b>	

☐ **Urgent**    ☐ **For Review**    ☐ **Please Comment**    ☐ **Please Reply**    ☐ **Please Recycle**

**• Comments:**

With respect to:

In Re the Application of: **TSUGA et al.**

Group Art Unit: 1746

U.S. Patent Application No.: 10/085,753

Examiner: Michael Kornakov

Filed: February 28, 2002

Attorney Docket No.: TI-31620

Title: METHOD AND DEVICE FOR REMOVING PARTICLES ON SEMICONDUCTOR WAFERS

Please find:

1. Petition For Extension of Time
2. Amendment in response to the Office Action dated June 18, 2004

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**DEC 20 2004**

**PATENT**  
**Attorney Docket No. TI-31620**  
**Application No.: 10/085,753**  
**Customer No.: 23494**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of:	)	
	)	
<b>TSUGA et al.</b>	)	Group Art Unit: 1746
	)	
Application No.: 10/085,753	)	Examiner: Michael Komakov
	)	
Filed: February 28, 2002	)	
	)	
For: METHOD AND DEVICE FOR	)	
REMOVING PARTICLES ON	)	
SEMICONDUCTOR WAFERS	)	

Assistant Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In reply to the Office Action dated June 18, 2004, the period for reply having been extended for three months, December 18 being a Saturday, by a request for extension of time filed concurrently herewith, please amend the application as follows:

**Amendments to the claims begin on page 2 of this paper.**

**Remarks begin on page 5 of this paper.**